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Inline Evaporation System for CIGS Thin-Film Solar
The inline co-evaporation tool is based on the thermal evaporation of all CIGS-related precursor materials. It is dedicated to the deposition of copper-indium-gallium-selenium layers for the purpose to form optimum precursor layers in the application of CIGS-thin-film solar cells.

The evaporation system consists of a handling station, multiple heating/cooling stations and deposition-chambers.

The inline evaporation system is offering proven thermal deposition technology, that delivers a high material utilization and excellent layer uniformity. In combination with a high uptime and mechanical yield, the system leads to a highly optimized and flexible production platform.
Main Features

→ Inline evaporation tool with high throughput capability
→ Modular chamber design supports a flexible layout conception to meet the production requests of the customer
→ Optimized evaporation source utilization through unique chamber design (minimized wall deposition)
→ High deposition speed and repeatability
→ Excellent flux uniformity
→ Easy and fast source refilling/replacement due to user-friendly source positioning
→ Optimized maintenance concept for maximum machine availability/uptime
→ High deposition speed
→ Excellent temperature uniformity during process sequence
→ Substrate pre-heating
→ In-situ monitoring of flux and temperature
→ Proven safety concept based on solid risk management and safety engineering

Key Components

The evaporation system consists of the following key components:

→ Handling section
  Transport of the substrates between the fab-automation and the evaporation system, including load-/unload of the process carriers
→ Process section
  Entrance load lock and pre-heating chamber provide the necessary vacuum level and apply an initial temperature profile for the consecutive process steps
→ Deposition Chambers
  Integrated multiple chamber system with heating - deposition - cooling capability. Chambers designed for excellent temperature uniformity and excellent deposition of different materials by optimized deposition-speed and geometry to achieve high repeatable precursor layers
→ Cooling Chamber and Exit Chamber
  Substrate cooling and exit on pre-defined temperature
→ Periphery
  Handling system
  Vacuum system
  Cold Traps (in front of TMPs)
  Metrology

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Technical Data

<table>
<thead>
<tr>
<th>Material</th>
<th>Copper, Indium, Gallium and Selenium deposition on glass substrates</th>
</tr>
</thead>
<tbody>
<tr>
<td>Substrate Dimensions</td>
<td>max. 1200 x 1600 mm² (other substrate sizes on request)</td>
</tr>
<tr>
<td>Substrate Thickness</td>
<td>2-3 mm</td>
</tr>
<tr>
<td>Footprint</td>
<td>depending on requested throughput</td>
</tr>
<tr>
<td>Cycle Time</td>
<td>depending on process requirements and requested throughput</td>
</tr>
<tr>
<td>Uptime [SEMI E10]</td>
<td>85 %</td>
</tr>
<tr>
<td>Main Voltage</td>
<td>400 V 3 AC/PE 50/60 Hz</td>
</tr>
<tr>
<td>Other Required Utilities</td>
<td>Cooling water, compressed air, process gases</td>
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</tbody>
</table>
SINGULUS TECHNOLOGIES – Innovations for New Technologies

SINGULUS TECHNOLOGIES develops and assembles innovative machines and systems for efficient and resource-saving production processes, which are used worldwide in the solar, semiconductor, medical technology, consumer goods and data storage.

The company’s core competencies include various processes of coating technology, surface treatment and wet-chemical and thermal production processes.